

Inscription(s)

process. Type IIa INTERNATIONAL GEMOLOGICAL INSTITUTE

ELECTRONIC COPY

LABORATORY GROWN DIAMOND REPORT

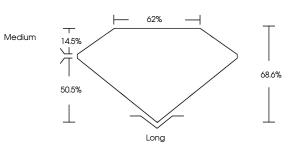
September 24, 2024

September 24, 2024		
IGI Report Number	LG652475530	
Description	LABORATORY GROWN DIAMOND	
Shape and Cutting Style	EMERALD CUT	
Measurements	6.60 X 4.87 X 3.34 MM	
GRADING RESULTS		
Carat Weight	1.03 CARAT	
Color Grade	F ICI F	
Clarity Grade	VVS 2	
Cut Grade	VERY GOOD	
ADDITIONAL GRADING II	NFORMATION	
Polish	EXCELLENT	
Symmetry	EXCELLENT	
Fluorescence	NONE	

Comments: This Laboratory Grown Diamond was created by Chemical Vapor Deposition (CVD) growth

131 LG652475530

PROPORTIONS



LG652475530

Report verification at igi.org

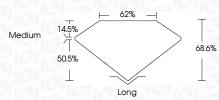


1691 LG652475530



September 24, 2024

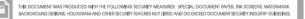
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Comments: This Laboratory created by Chemical Vapa process. Type IIa	



GHIJ	Faint	Very Light	Light
W/S ^{1 - 2}	VS ¹⁻²	SI ¹⁻²	1 ¹⁻³
Very Very Slightly Included	Very Slightly Included	Slightly Included	Included
	2 H 1 1 1 1 1 1		
GI 2020, International G	emological Institute		FD - 10 20
	WS ¹⁻² Very Very Slightly Included	VVS ¹⁻² VS ¹⁻² Very Very Slightly Included Slightly Included	VVS ¹⁻² VS ¹⁻² SI ¹⁻² Very Very Slightly Included Very Slightly Included Slightly Included



LABORATORY GROWN DIAMOND REPORT

ADDITIONAL GRADING INFORMATION



M	1.03 CARAT		W52	VERY GOOD	68.6%	\$29	Medlum	Buoj	EXCELLENT	EXCELLENT	NONE	MBN LG652475530	Comments: This Laboratory Grown Diamond was created by Chemical Vapor Deposition (CVD) growth process.
6.60 X 4.87 X 3.34 MM	Carat Welaht	Color Grade	Clarity Grade	Cut Grade	Depth	Table	Girdle	Culet	Polish	Symmetry	Fluorescence	Inscription(s)	Comments: This Laboratory Grown Dramond was created by Chemical Vapor Deposit (CVD) growth process. Type Ita